



## MEMS Inertial Sensors

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Deadline for manuscript  
submissions:

**closed (28 February 2023)**

### Message from the Guest Editors

Dear Colleagues,

MEMS technology is revolutionary to inertial measurement because of its unique advantages, i.e., miniaturized size, low power consumption, high dynamic range and low costs. It is particularly suitable for navigation and control systems in robotics, autonomous car, personal indoor scenario and some other military applications. Even though, MEMS inertial sensors still suffers scientific barriers towards high-end applications. Major challenges include but are not limited to: microfabrication processes, new materials, device design and optimization, simulation techniques, interface circuits, measurement instrumentation, signal processing and sensors fusions. This Special Issue calls for the original research papers and reviews with the state-of-the-art results in the relevant topics.





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